



ATTORNEY DOCKET NO. 55071-280

PATENT

In re Application of: )  
J. Fung CHEN, et al. ) Customer No.: 20277  
Serial No.: 10/662,365 ) Confirmation No.: 9422  
Filed: September 16, 2003 ) Group Art Unit: 1756  
FOR: HYBRID PHASE-SHIFT MASK ) Examiner: STEPHEN D. ROSASCO

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Mail Stop 313(c)  
Hon. Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F.R. § 1.56, the attention of the Patent and Trademark Office is directed to the cited reference(s) listed on the attached PTO-1449. The cited references are believed to be the most relevant known to Applicants and/or Assignee at this time concerning the invention as claimed in the above-captioned patent application. No representation is made or intended that more relevant information does not exist or that the order of presentation of the information in any way reflects their relative pertinence.

Applicant(s) respectfully request(s) that each of the cited information be expressly considered during the prosecution of this application and that the cited reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom. A copy of each reference is attached.

[ ] 1. This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. Thus, no certification or fee is required.

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b. I hereby certify that no item of information in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to my knowledge after making reasonable inquiry, was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this Information Disclosure Statement. 37 C.F.R. § 1.97(e)(2).

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a. I hereby certify that each item of information contained in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement. 37 C.F.R. § 1.97(e)(1).

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Please grant any extension of time deemed necessary for entry of this communication. Please charge any deficient fees, or credit any overpayment of fees associated with this communication to Deposit Account No. 50-0417. A duplicate copy of this communication is attached.

Respectfully submitted,

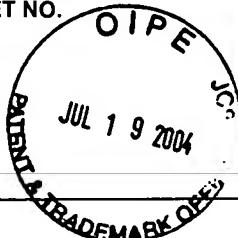
McDERMOTT WILL & EMERY

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LIST OF REFERENCES CITED BY APPLICANT  
(Use Several Sheets if Necessary)

## APPLICANT

J. Fung CHEN, et al.

FILING DATE September 1, 2003

GROUP  
1756

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	FILING DATE IF APPROPRIATE
	AA	5,302,477	4/12/94	Dao et al.	
	AB	5,348,826	9/20/94	Dao et al.	
	AC	5,354,632	10/11/94	Dao et al.	
	AI	5,384,219	1/24/95	Dao et al.	
	AJ	5,618,643	4/8/97	Dao et al.	
	AK	5,633,102	5/27/97	Toh et al.	
	AT	6,458,495	10/1/02	Tsai et al.	

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO
	AL				
	AM				
	AN				
	AO				

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

	AR	Toh, et al., "Optical Lithography with Chromeless Phase-Shifted Masks", SPIE Vol. 1463, pp.74-86.
	AP	Levenson, et al., "SCAA Mask Exposures and Phase Phirst Design for 110nm and Below", Proc. SPIE Vol. 4346, pp.817-826.
	AS	Watanabe, et al., "Sub-quarter-Micron Gate Pattern Fabrication Using a Transparent Phase Shifting Mask", J. Vac. Sci. Technol. B, Vol. 9, No. 6, Nov/Dec 1991, pp. 3172-3175.
	AT	Watanabe, et al., "Transparent Phase Shifting Mask", IEDM 90, pp. 33.2.1 to 33.2.4.

## EXAMINER

## DATE CONSIDERED

\*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.